

Form PTO-1448 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE				ATTY. DOCKET NO. M122-2067	SERIAL NO. 10/62434D Filing Under 35 U.S.C. § 111(b)		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Brent A. McClure et al			
				FILING DATE Filed Herewith	GROUP Unknown 2831		
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
/NH/	AA	6,180,481	1/01	DeBoer et al			
	AB	6,218,256	4/01	Agarwal			
	AC	6,204,049	8/00	Solsyappan 6,104,049			
	AD	6,180,447	1/01	Park			
	AE	6,274,428	8/01	Wu			
	AF	6,124,158	9/00	Dautartas et al			
	AG	6,144,060	11/00	Park			
	AH	5,316,982	5/94	Taniguchi			
✓	AJ	6,281,142	6/99	Basceri et al	8/28/2001		
✓	AJ	6,204,172	9/01	Marah	3/20/2001		
▼	AK	5,432,732	7/95	Ohmi			
/NH/	AL	6,242,299	06/01	Hickert			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes
							No
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
/NH/	AR		A.W. Ott, et al., "Atomic layer controlled deposition of Al ₂ O ₃ films using binary reaction sequence chemistry" Applied Surface Science (107) 1996, pp. 128-136.				
	AS						
EXAMINER /Nguyen Ha/			DATE CONSIDERED		06/20/2007		
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